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(12) **United States Design Patent**  
**Yamaguchi et al.**

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(54) **AIR FLOW CONTROLLER FOR HEATER OF SUBSTRATE PROCESSING APPARATUS**

(71) Applicant: **Hitachi Kokusai Electric Inc.**, Tokyo (JP)

(72) Inventors: **Takatomo Yamaguchi**, Toyama (JP); **Tetsuya Kosugi**, Toyama (JP); **Shuhei Saïdo**, Toyama (JP)

(73) Assignee: **HITACHI KOKUSAI ELECTRIC INC.**, Tokyo (JP)

(\*\*) Term: **15 Years**

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(30) **Foreign Application Priority Data**

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(51) **LOC (11) Cl.** ..... **13-03**

(52) **U.S. Cl.**  
USPC ..... **D13/182**

(58) **Field of Classification Search**  
USPC ..... D13/123-132, 154, 184, 199; D15/138, D15/140, 144.1  
CPC ..... H01L 21/67011; H01L 21/67098; H01L 21/67103; H01L 21/67109; H01L 21/67115

See application file for complete search history.

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*Primary Examiner* — Thomas Johannes

*Assistant Examiner* — Lauren McVey

(74) *Attorney, Agent, or Firm* — Fitch, Even, Tabin & Flannery, LLP

(57) **CLAIM**

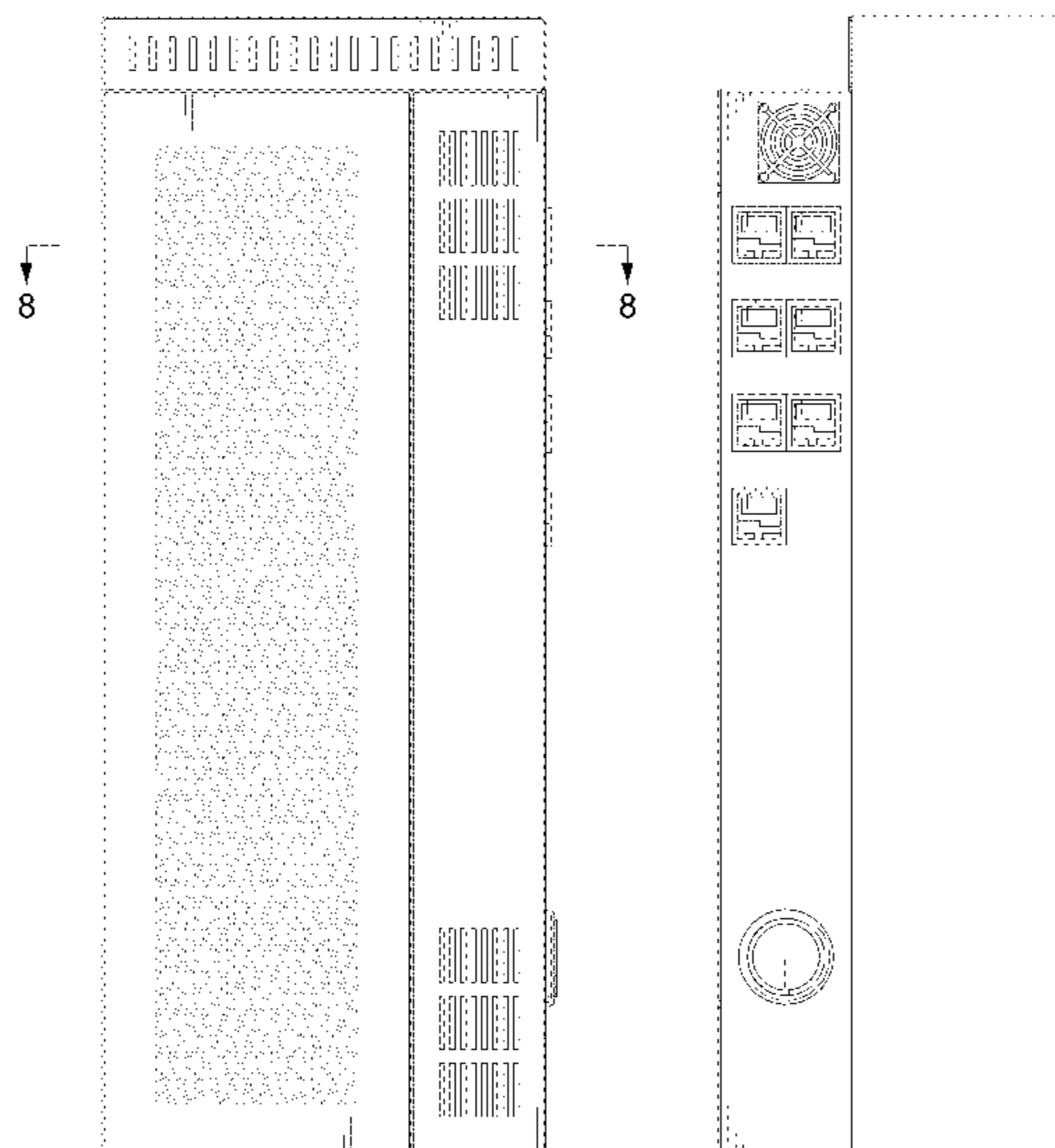
We claim the ornamental design for an air flow controller for heater of substrate processing apparatus, as shown and described.

**DESCRIPTION**

FIG. 1 is a front, bottom and right side perspective view of an air flow controller for heater of substrate processing apparatus showing our new design;  
 FIG. 2 is a front elevational view thereof;  
 FIG. 3 is a rear elevational view thereof;  
 FIG. 4 is a left side elevational view thereof;  
 FIG. 5 is a right side elevational view thereof;  
 FIG. 6 is a top plan view thereof;  
 FIG. 7 is a bottom plan view thereof; and,  
 FIG. 8 is a cross-sectional view taken in the direction of line 8-8 in FIG. 2.

The broken lines immediately adjacent to the shaded areas represent the bounds of the claimed design while all other broken lines are directed to environment; the broken lines form no part of the claimed design.

**1 Claim, 5 Drawing Sheets**



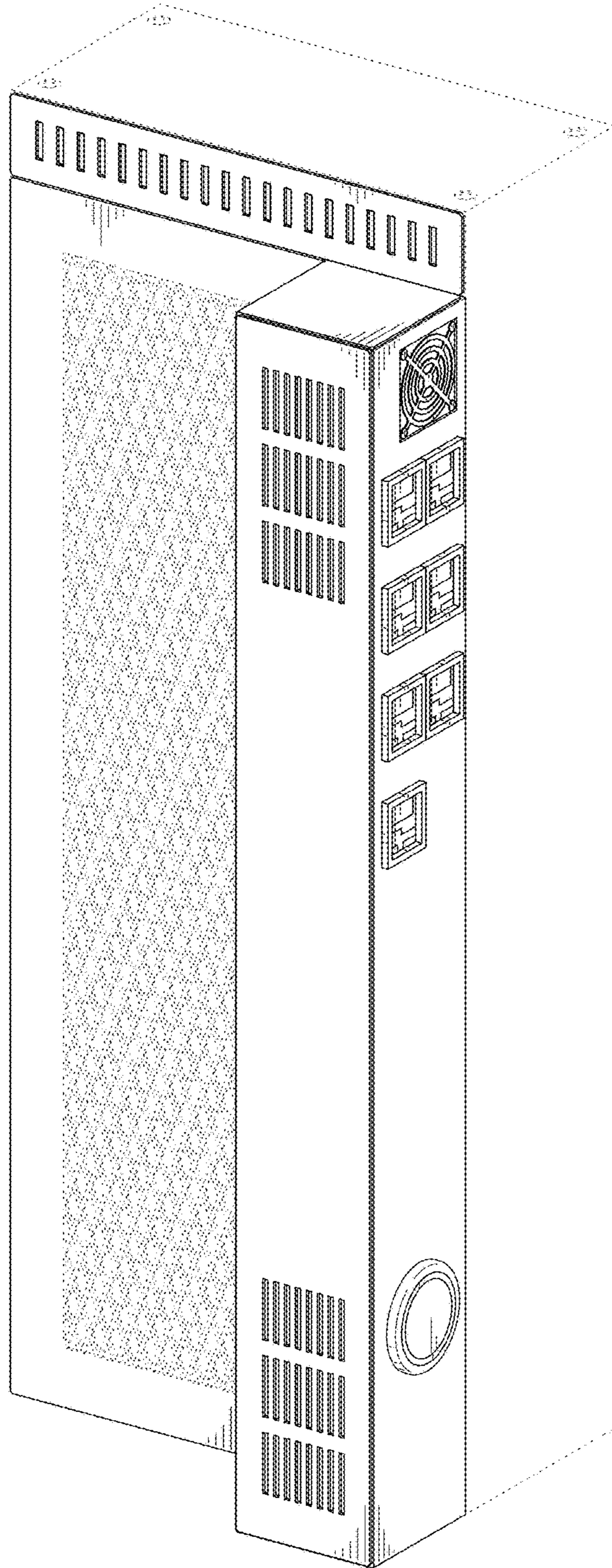


FIG. 1



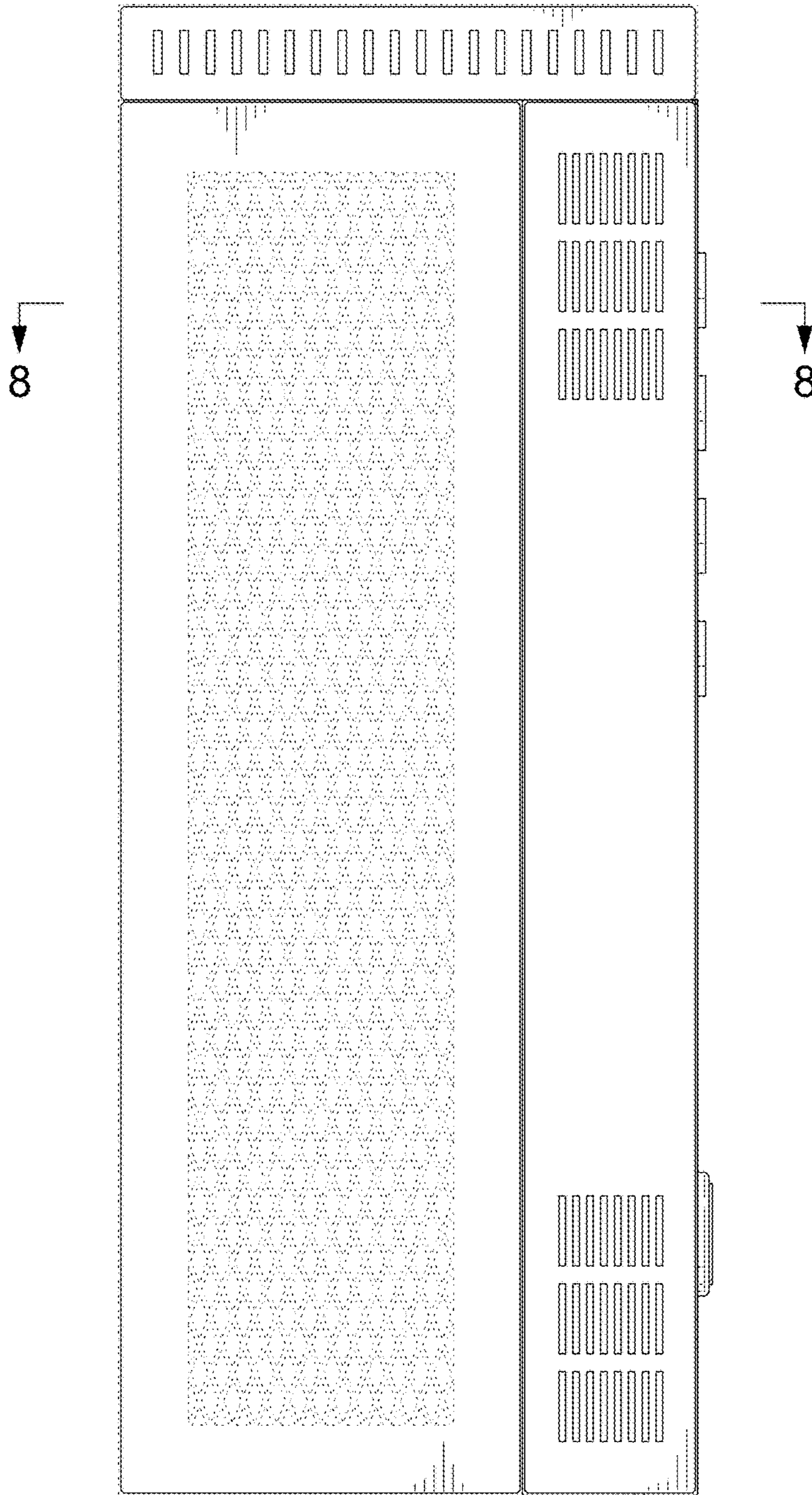


FIG. 2

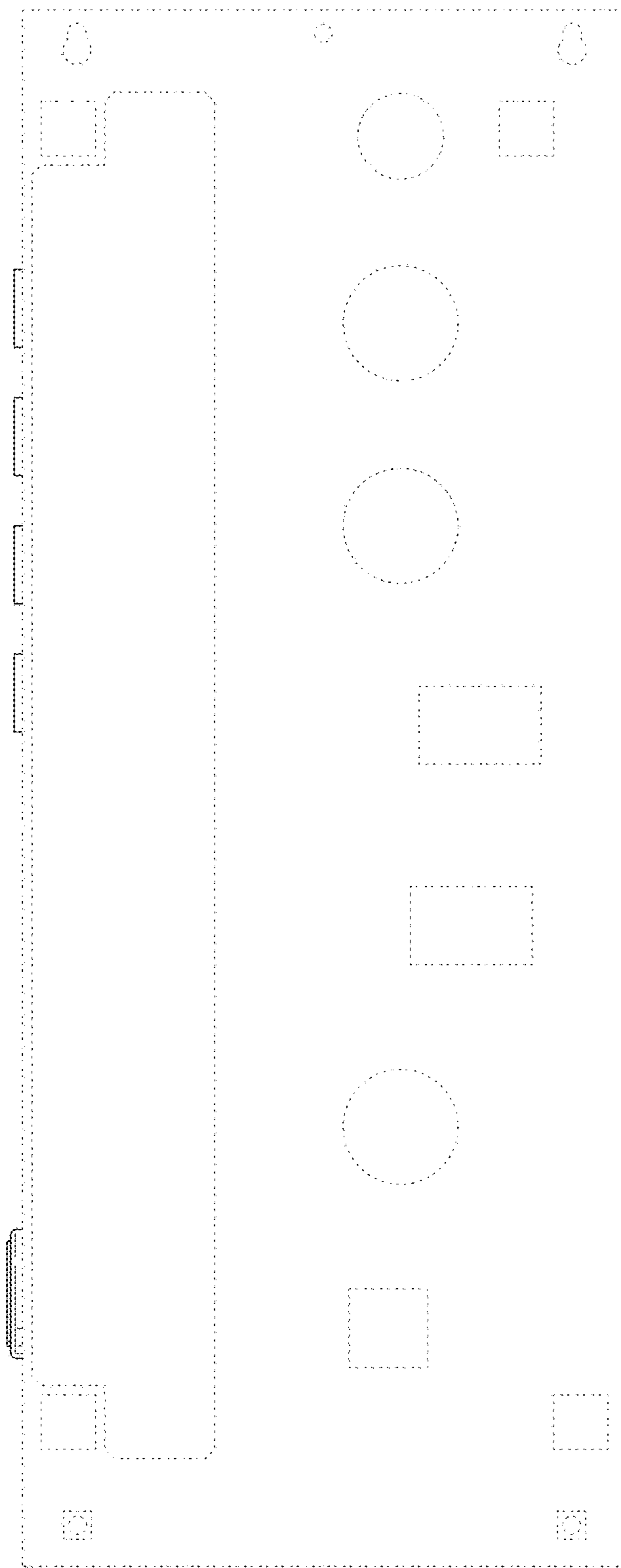


FIG. 3

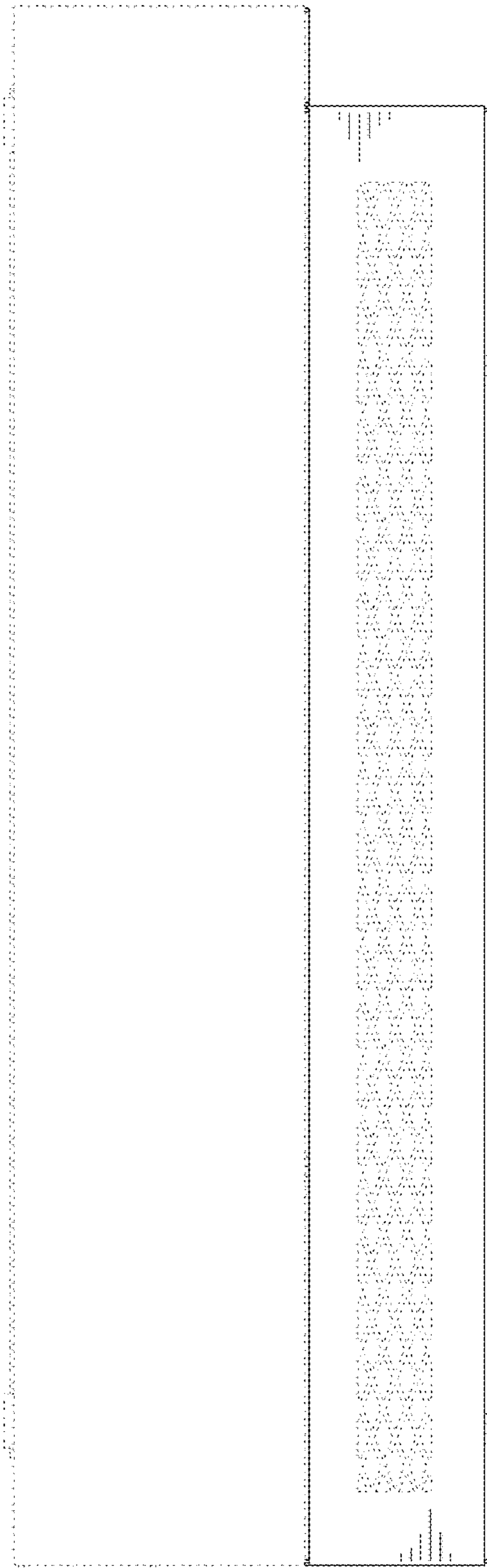


FIG. 4

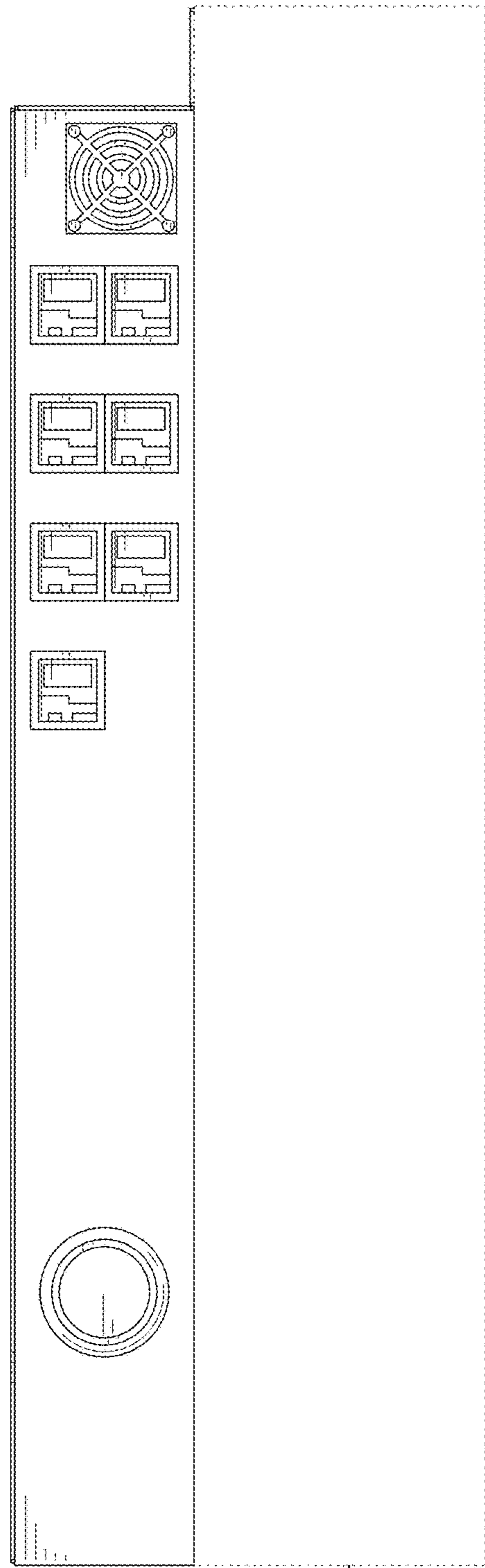


FIG. 5

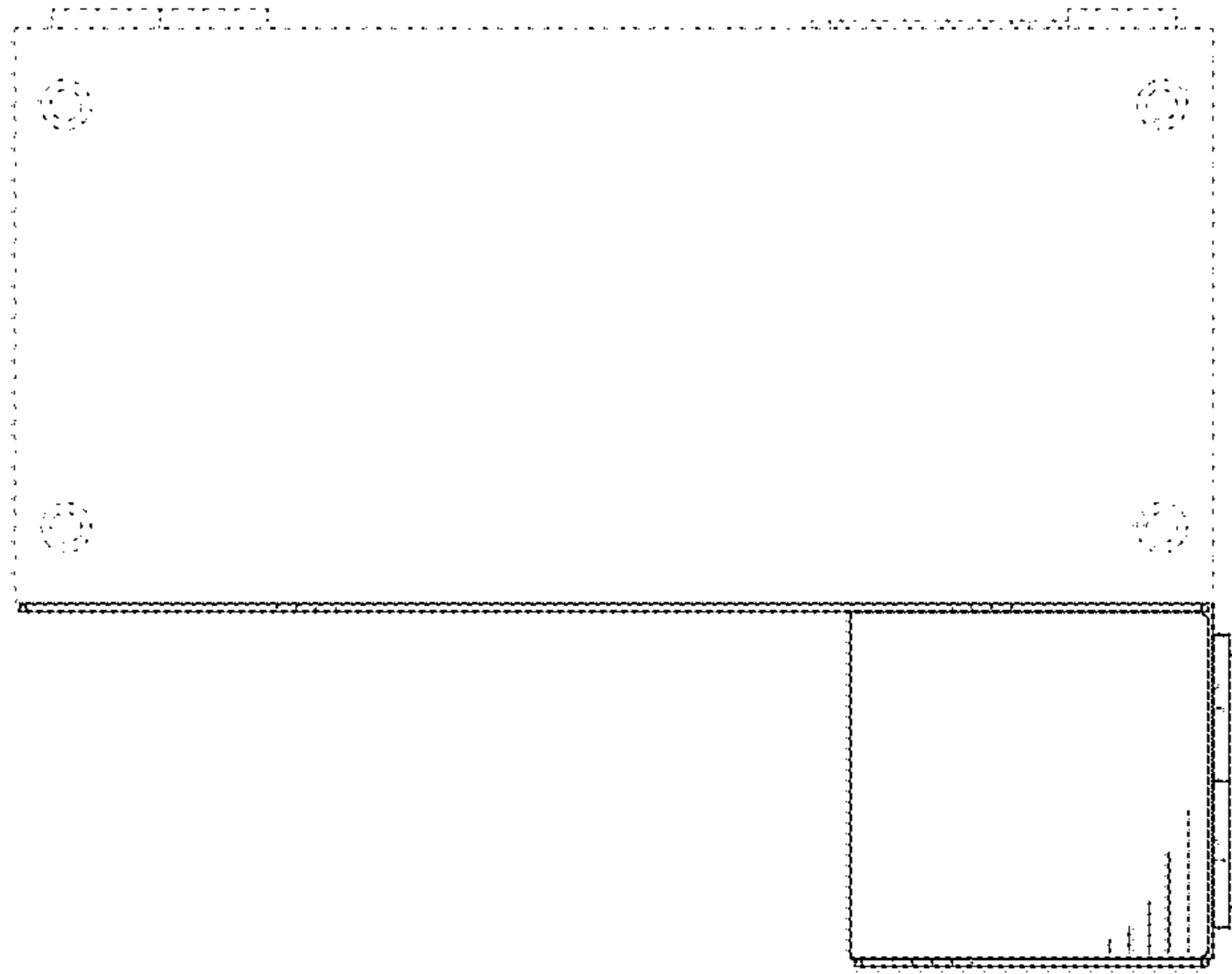


FIG. 6

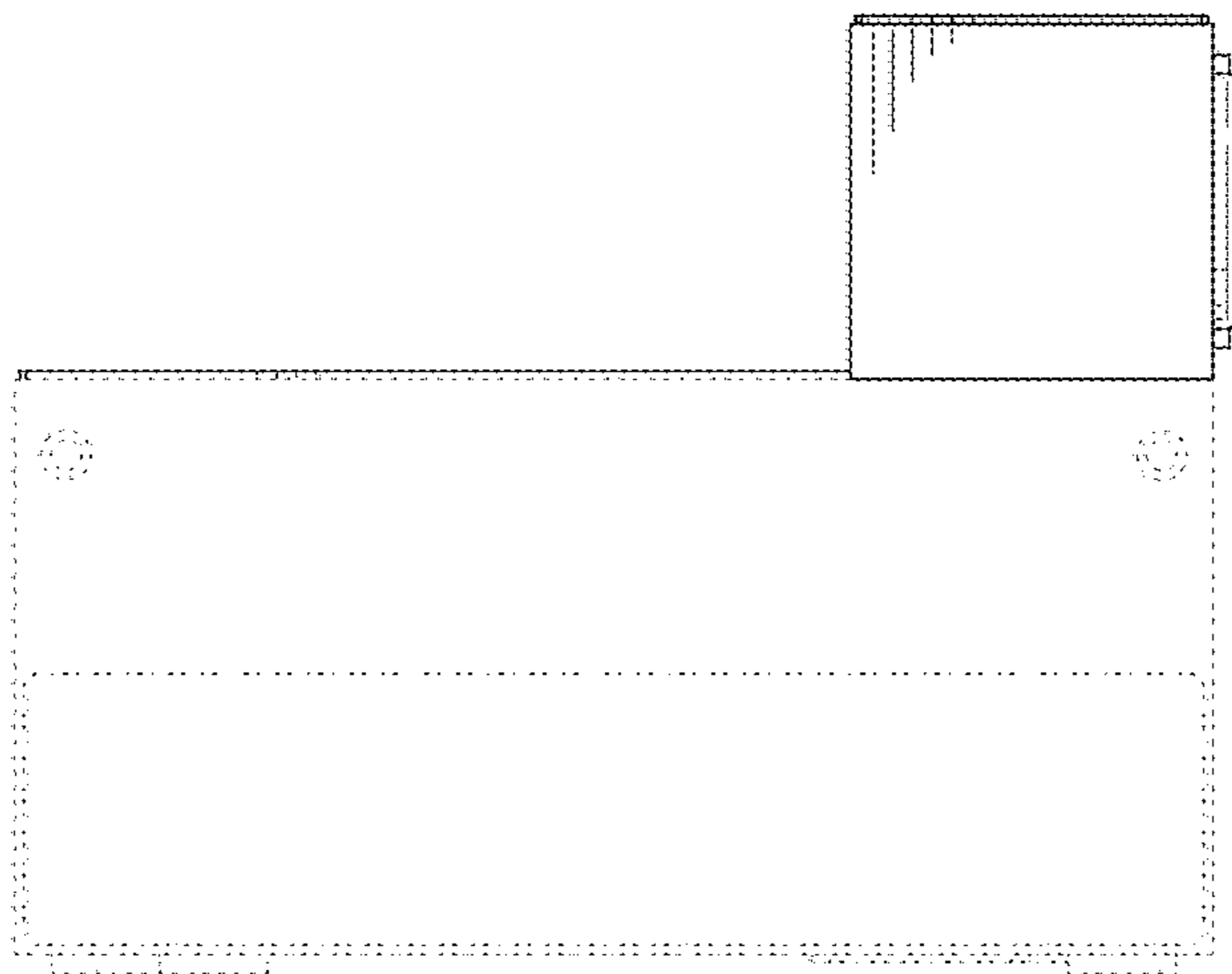


FIG. 7

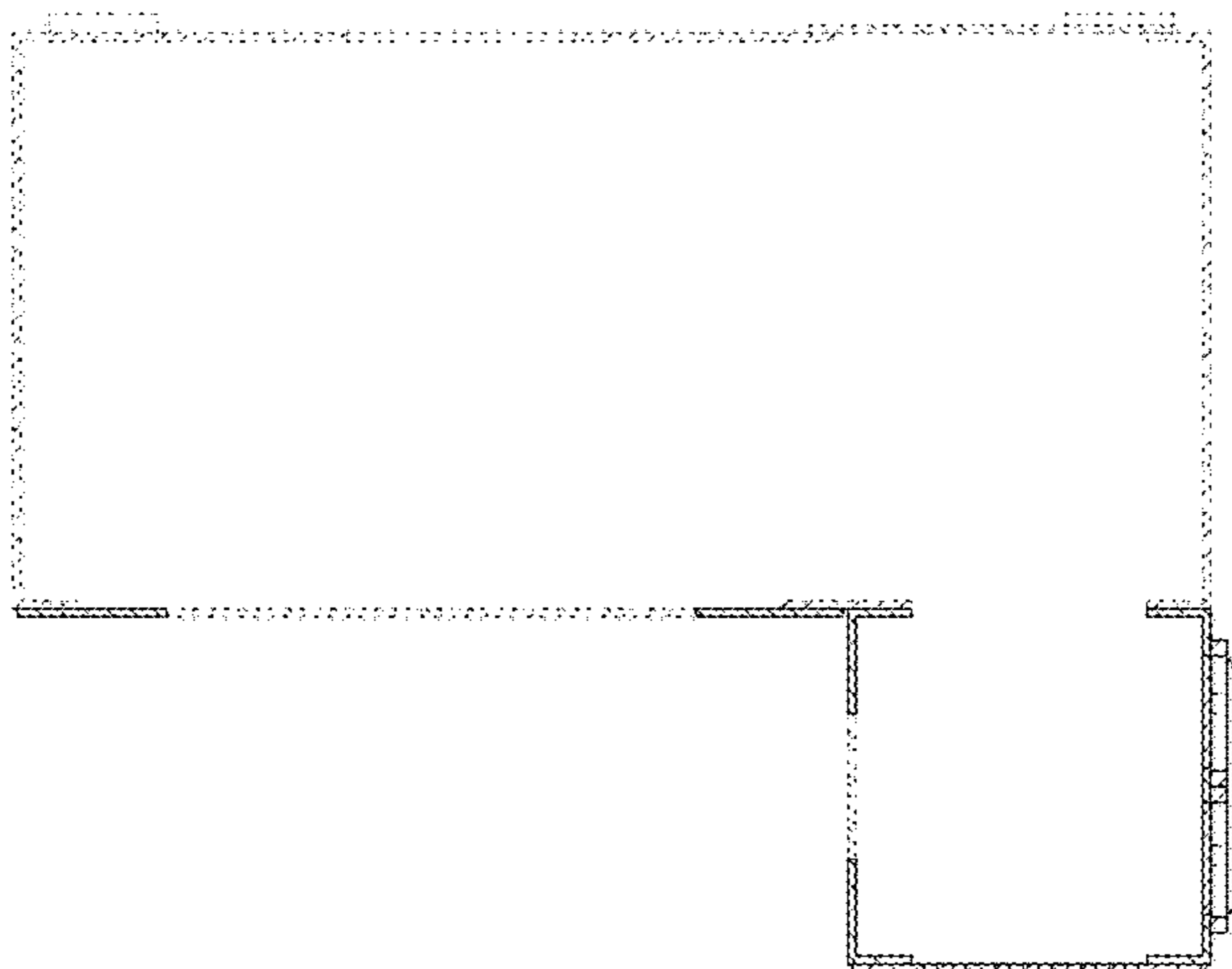


FIG. 8